

# YES - YES3TA HMDS Oven - HA

Equipment	YES YES3TA HMDS Oven
Process Area	LITHOGRAPHY
Location	Primary lithography, clean room
Assessed By	Breanna Cherkawski
Date of Assessment	01 Mar 2024
Final Assessment	MEDIUM



**Please Review**

Carefully review and familiarize yourself with the hazard assessment applicable to your tool or process.